| Ref<br># | Hits  | Search Query  | DBs   | Default<br>Operator | Plurals | Time Stamp       |
|----------|-------|---|---|---------------------|---------|------------------|
| L6       | 2     | ("6476988").PN.   | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | OFF     | 2006/12/28 14:24 |
| S95      | 53    | (hydrophob\$3) with bank and tft  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 16:19 |
| S94      | 269   | (hydrophob\$3) and tft and bank   | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 16:18 |
| S91      | 405   | (hydrophob\$3 hydrophil\$3) and tft and bank  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 16:15 |
| S93      | 88    | S91 and (Uv and (oxygen "O.sub.<br>2"))   | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 14:22 |
| S92      | 71    | S91 and (Uv and (oxygen near3 plasma "O.sub.2"))  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 14:22 |
| S83      | 24    | (Uv near3 radiation and (oxygen<br>near3 plasma "O.sub.2")) with<br>(substrate wafer) and (ink near3<br>jet)                                  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 14:22 |
| S84      | 15879 | ((Uv near3 radiation and (oxygen<br>near3 plasma "O.sub.2")) with<br>(substrate wafer)) or (hydrophob\$3<br>hydrophil\$3) and (ink near3 jet) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR                  | ON      | 2006/12/27 14:21 |

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| S90 | 11    | freeze near3 drying with emitt\$3   | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 14:17 |
| S89 | 0     | freeze near3 drying with tft  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 14:17 |
| S88 | 0     | freeze near3 drying with (cathode electrode annonde) and tft  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 14:16 |
| S87 | 54    | freeze near3 drying with (cathode electrode annonde)  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 14:16 |
| S86 | 3029  | (((Uv near3 radiation and (oxygen near3 plasma "O.sub.2")) with (substrate wafer)) or (hydrophob\$3 hydrophil\$3)) and (ink near3 jet) and (glass or acry\$3) near3 (substrate wafer) | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 14:12 |
| S85 | 15688 | (((Uv near3 radiation and (oxygen<br>near3 plasma "O.sub.2")) with<br>(substrate wafer)) or (hydrophob\$3<br>hydrophil\$3)) and (ink near3 jet)                                       | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 14:11 |
| S80 | 215   | (Uv near3 radiation and (oxygen near3 plasma "O.sub.2")) with (substrate wafer)   | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 13:55 |
| S82 | 5     | (Uv near3 radiation and (oxygen<br>near3 plasma "O.sub.2")) with<br>affinity  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR          | ON | 2006/12/27 10:49 |

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| S81 | 2    | ("20040245903").PN.                                  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | OFF | 2006/12/27 10:03 |
| S79 | 409  | S78 and ((@ad<"20040325") or (@rlad<"20040325"))     | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON  | 2006/12/27 09:55 |
| S78 | 467  | S77 and (annode cathode electrode)                   | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON  | 2006/12/26 10:58 |
| S74 | 4538 | S73 and ((@ad<"20040325") or<br>(@rlad<"20040325"))  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON  | 2006/12/26 10:58 |
| S77 | 824  | (UV and (Oxygen near3 plasma "O. sub.2")) same glass | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON  | 2006/12/26 10:57 |
| S76 | 2    | ("20040245903").PN.                                  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | OFF | 2006/12/26 10:56 |
| S75 | 8    | (lyophiliz\$3 and lyophob\$3) and electrode          | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON  | 2006/12/26 10:45 |
| S73 | 4980 | (lyophiliz\$3 lyophob\$3) and electrode              | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON  | 2006/12/26 10:33 |

| S72 | 13     | S71 and ((@ad<"20040325") or<br>(@rlad<"20040325"))                  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2006/12/26 10:33 |
|-----|--------|--|---|----|----|------------------|
| S71 | 50     | (lyophiliz\$3 lyophob\$3) and electrode and electro\$3 near3 emitter | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2006/12/26 10:32 |
| S70 | 4980   | (lyophiliz\$3 lyophob\$3) and electrode                              | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2006/12/26 10:12 |
| S69 | 72256  | lyophiliz\$3 lyophob\$3  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2006/12/26 10:11 |
| S1  | 109361 | tft or thin adj film adj transistor                                  | US-PGPUB;<br>USPAT;<br>USOCR;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2006/12/26 09:46 |